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**Chi Fai Benny Cheung
Suet Sandy To**
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Contents

v	<i>Authors</i>
vii	<i>Conference Committee</i>
ix	<i>Introduction</i>

SIXTH ASIA PACIFIC CONFERENCE ON OPTICS MANUFACTURE

11383 02	Binocular vision physical coordinate positioning algorithm based on PSO-Harris operator [11383-5]
11383 03	Fabrication of multi-layer micropillars array in micro-grooving technology [11383-8]
11383 04	Vibration-resistant interferometric measurement of optical surface figure and roughness [11383-10]
11383 05	Dark field microscopy for ultra-precision surface processing defect measurement [11383-11]
11383 06	Analysis and optimization for a chordwise morphing wing with clearance joints [11383-12]
11383 07	Local field enhancement effect of the gold-coated nanoprobe [11383-16]
11383 08	Detection and analysis of surface defects on polished KDP crystal [11383-19]
11383 09	Modeling and experiment of concave microlens array on silicon wafer by grinding-polishing process with diamond slurry [11383-20]
11383 0A	Focusing characteristics optimization of composite near-field fiber probe based on surface plasmon [11383-21]
11383 0B	A single mirror magnifier with freeform surfaces using radial basis functions based on surface slope [11383-22]
11383 0C	Research progress on optical system of polarization LIDAR [11383-23]
11383 0D	An investigation of slurry erosion analysis for disc hydrodynamic polishing [11383-24]